

| L Number | Hits | Search Text | DB | Time stamp |
|-------------|-------|--|---------------------------------|---------------------|
| - | 11902 | (ion adj beam) and etching | USPAT; US-PGPUB; EPO; JPO | 2003/07/17 11:43 |
| - | 5806 | ((ion adj beam) and etching) and electrode | USPAT; US-PGPUB; EPO; JPO | 2003/07/17 10:08 |
| - | 2485 | ((ion adj beam) and etching) and electrode) and frequency | USPAT; US-PGPUB; EPO; JPO | 2003/07/17 10:08 |
| - | 146 | ((ion adj beam) and etching) and electrode) and frequency) and (acoustic adj wave) | USPAT; US-PGPUB; EPO; JPO | 2003/07/17 10:09 |
| - | 1 | ((ion adj beam) and etching) and electrode) and frequency) and (acoustic adj wave)) and (piezoelectric adj oscillator) | USPAT; US-PGPUB; EPO; JPO | 2003/07/17 10:19 |
| - | 4 | ((ion adj beam) and etching) and electrode) and frequency) and (piezoelectric adj oscillator) | USPAT; US-PGPUB; EPO; JPO | 2003/07/17 10:19 |
| - | 117 | ((ion adj beam) and etching) and electrode) and frequency) and (acoustic adj wave)) and piezoelectric | USPAT; US-PGPUB; EPO; JPO | 2003/07/17 10:34 |
| - | 3 | ((ion adj beam) and etching) and electrode) and frequency) and (acoustic adj wave)) and piezoelectric) and (moving near4 direction) | USPAT; US-PGPUB; EPO; JPO | 2003/07/17 11:41 |
| - | 77 | ((ion adj beam) and etching) and electrode) and frequency) and (acoustic adj wave)) and piezoelectric) and direction | USPAT; US-PGPUB; EPO; JPO | 2003/07/17 10:37 |
| - | 45 | ((ion adj beam) and etching) and electrode) and frequency) and (acoustic adj wave)) and piezoelectric) and direction) and (moving or translation) | USPAT; US-PGPUB; EPO; JPO | 2003/07/17 11:54 |
| - | 118 | ((ion adj beam) and etching) and electrode) and frequency) and (moving near4 direction) | USPAT; US-PGPUB; EPO; JPO | 2003/07/17 11:53 |
| - | 7 | ((ion adj beam) and etching) and electrode) and frequency) and (moving near4 direction)) and translation | USPAT; US-PGPUB; EPO; JPO | 2003/07/17 11:42 |
| - | 20 | ((ion adj beam) and etching) and electrode) and frequency) and (moving near4 direction)) and (ion adj beam adj etching) | USPAT; US-PGPUB; EPO; JPO | 2003/07/17 11:48 |
| - | 695 | ((ion adj beam) and etching) and electrode) and frequency) and (ion adj beam adj etching) | USPAT; US-PGPUB; EPO; JPO | 2003/07/17 11:48 |
| - | 1 | ((ion adj beam) and etching) and electrode) and frequency) and (ion adj beam adj etching)) and (irradiating near4 electrode) | USPAT; US-PGPUB; EPO; JPO | 2003/07/17 11:50 |
| - | 14 | ((ion adj beam) and etching) and electrode) and frequency) and (ion adj beam adj etching)) and (irradiating near4 substrate) | USPAT; US-PGPUB; EPO; JPO | 2003/07/17 11:50 |
| - | 1 | ((ion adj beam) and etching) and electrode) and frequency) and (ion adj beam adj etching)) and (irradiating near4 substrate)) and (moving near4 direction) | USPAT; US-PGPUB; EPO; JPO | 2003/07/17 11:53 |

| | | | | |
|---|-----|--|---------------------------------|---------------------|
| - | 4 | (((((ion adj beam) and etching) and electrode) and frequency) and (ion adj beam adj etching)) and (irradiating near4 substrate)) and (moving or translation) | USPAT; US-PGPUB; EPO; JPO | 2003/07/17 11:56 |
| - | 185 | (((((ion adj beam) and etching) and electrode) and frequency) and (ion adj beam adj etching)) and (moving or translation) | USPAT; US-PGPUB; EPO; JPO | 2003/07/17 11:57 |
| - | 177 | (((((ion adj beam) and etching) and electrode) and frequency) and (ion adj beam adj etching)) and (moving or translation)) and substrate | USPAT; US-PGPUB; EPO; JPO | 2003/07/17 11:59 |
| - | 177 | ((((((ion adj beam) and etching) and electrode) and frequency) and (ion adj beam adj etching)) and (moving or translation)) and substrate) and (ion adj beam) | USPAT; US-PGPUB; EPO; JPO | 2003/07/17 11:59 |
| - | 62 | ((((((ion adj beam) and etching) and electrode) and frequency) and (ion adj beam adj etching)) and (moving or translation)) and substrate) and (ion adj beam)) and stage | USPAT; US-PGPUB; EPO; JPO | 2003/07/17 13:59 |